We claim:

1. A method for making an electrode, comprising synthesizing a precursor solution, said precursor solution selected from an anode precursor solution and a cathode precursor solution, wherein said anode precursor solution is formed by dissolving $Sn(OCH_2C(CH_3)_3)_2$ in a solvent in the presence of HO_2CCH_3 and wherein said cathode precursor solution is formed by dissolving a mixture of $(Li(OCH_2C(CH_3)_3))_8$ and $Co(O_2CCH_3)_2 \cdot H_20$ in at least one polar solvent, depositing at least one thin film layer using said precursor solution, and heating said at least one thin film layer to a temperature greater than approximately 650°C.
2. The method of claim 1 wherein said solvent is selected from toluene, hexane, tetrahydrofuran, and pyridine.
3. The method of claim 1 wherein said at least polar solvent is selected from pyridine, tetrahydrofuran, and toluene.
4. The method of claim 1 wherein said at least one thin film layer has a thickness between approximately 500 Å and 1000 Å.
5. The method of claim 1 wherein said step of depositing at least one thin film layer is performed using a spin-coat deposition technique.
6. The method of claim 1 wherein said step of depositing at least one thin film is performed in the presence of water vapor.